The Model 8060 probe station offers the highest performance available in a 6 - 8” (150 - 200mm) manual analytical probe station. The 8060 is designed for ease of use in demanding applications such as very low current and voltage probing, high and low temperature probing, and sub micron target probing to the limits of visible optics. The 8060 station combines the value of efficient use with the confidence of consistent, accurate electrical and mechanical performance, and is the manual 150 / 200mm probe station of choice for demanding analytical test professionals around the world.

Available options for the model 8060 probe station allow you to configure it for your specific needs. Probe card holders, thermal chucks, manipulators, unique probe holders, vibration isolation tables, light tight enclosures (LTEs) and camera systems are popular accessory options. The 8060 may also be configured with an integrated environment that supports dark - shielded - dry probing.

The price-performance value of the model 8060 coupled with low cost - of - ownership from its high efficiency features and rugged reliability combine to make it a truly cost effective answer for high performance analytical probing.
8060 Features and Benefits

- Manual lead screw control of stage. Features coaxial fast and fine resolution controls for both fast wafer transition and high resolution sub-micron probing.
- Lead screw control of platen for probe card positioning.
- Leadscrew driven high resolution manual chuck theta control.
- High resolution compound microscopes supported by high stability bridge. Stereo Zoom microscopes optional.
- Includes fast platen lift with adjustable microscope lift delay.
- Includes independent microscope lift standard.
- Ergonomic, intuitive, compact design enhances ease of use while increasing stability.
- Compact footprint for efficient use of lab space.
- Large magnetic stainless steel platen with removable loading wedge allows operators to choose from a variety of convenient manipulator placement options.
- 6-inch (150mm) or 8-inch (200mm) ambient vacuum chuck with full wafer coverage stage travel.
- Optional hot or hot/cold chuck may be added including internal cable/hose handling assembly with convenient termination at the rear of the probe station and integrated dark/dry environment.
- Single point ground - low current ready.

Station specifications:

Test Station Dimensions
- Footprint (Width x Depth) 22.75” x 23.35” (57.7 x 59.3cm).
- Station Width, Depth, Height 28.5” x 26.75” x 21.5” (72.3 x 67.9 x 54.6cm). Weight: 246 lb. (542.3 kg).

X-Y Stage Movement
- Cast stage cores for faster settling time.
- Cross roller bearing way construction for high reliability and precision.
- X and Y axis range 6” x 6” (150mm x 150mm) or 8” x 8” (200mm x 200mm). Manual control
- Resolution 3.5 µm fast, 0.38 µm fine control.

Chuck Theta:
- 100 TPI (0.7 µm) resolution, 15 degrees range.

Microscope
- Bridge mount with 4” x 4” x 2” (100 x 100 x 50mm) X, Y, Z range 2.5 µm resolution.

Large-area Magnetic Stainless Steel Platen
- 1.0” (25.4mm) Z axis range via platen fine lift control, resolution 0.1 µm per degree rotation.

Full range of accessories and options available including:
- Probe card holders, Light Tight Enclosures, Thermal Chucks, Video accessories, Manual/Motorized manipulators.

Specifications subject to change without notice.